# THERMAL ANALYSIS OF HIGH HEAT LOAD MIRRORS FOR THE IN-SITU NANOPROBE BEAMLINE

J. Knopp †, X. Shi, J. Maser, M. Fisher, R. Reininger, Z. Liu, Advanced Photon Source, Argonne National Laboratory, Lemont, USA † jknopp@anl.gov

## **ABSTRACT**

The Advanced Photon Source is currently in the process of upgrading to a multi-bend achromat storage ring, which will increase brightness and coherent flux by several orders of magnitude. The planned In-Situ Nanoprobe beamline, one of the feature beamlines of the APS Upgrade project, is a 220 m long beamline that aims to focus the x-ray beam to a spot size of 20 nm or below. In this beamline, a double-mirror system containing a high heat load mirror and a pink beam mirror is designed to provide high harmonic rejection and focus the beam to a beam-defining aperture (BDA). One of the key issues is to manage the high power and power density absorbed by these mirrors due to the new source. To attain the best focus at the BDA, the pink beam mirror needs to be mechanically bent to correct for thermal deformations on both mirrors. In this study we report on the thermal responses to different cooling schemes (e.g., side and internally water cooled) for

### **FOCAL SIZE COMPARISON**

RADIATION EQUIPMENT AND INSTRUMENTATION

Photon Energy	5 keV	7 keV	9 keV	12 keV
Total Power absorbed by M1 (W)	429	260	130	20.3



2018

Total Power absorbed by **ENERGY SCAN** THERMAL ANALYSIS 9.06 6.23 5.79 10.6 M2 (W) The ISN beamline will likely Finite Element Analysis was used to VBDA M2: bendable scan energies for some calculate thermal deformation on 55 m 29 m studies. Analysis was done to the surfaces of the M1 and M2 determine the change in focal mirrors. M1: flat spot size at the BDA when Focal Size at BDA (µm), 28 m 16.6 13.0 11.6 14.4 scanning energies. **FWHM** Theoretical Heat loads from the incident beam The scanning range looked at were calculated by SRCalc for **B: Steady-State Thermal** Temperature was between 5.0 and 5.1 keV. silicon mirrors. Both mirrors are Type: Temperature The bend of the M2 was held Unit: K assumed to be side cooled with Time: 1 constant at 4.38 km which is OHFC copper cooling blocks. Heat 299.31 Max optimized for 5 keV. loads were mapped between 5 keV 299.27 Focal Size at BDA (µm), 299.23 1129 FWHM Thermal Bump, No 589 257 and 12 keV at 1000 eV increments. 47 299.19 Correction 5.1 keV (no 299.16 5 keV correction on Photon energy 299.12 M2) Thermal contact resistance 299.08 299.04 between the silicon and copper was 299 298.97 Min designated to be 8000 W/m<sup>2</sup> [1].  $K_{v}$  for undulator U25 1.862 1.833 Focal Size at BDA (µm), thermal deformations Resultant FWHM, Thermal Bump, 14.2 11.6 16.8 13.0 were used to calculate the focal Corrected Total power absorbed by M1 (W) 429 418 spot size at the BDA. From the focal spot size the bending radius required to achieve focus was Total power absorbed by M2 (W) 10.6 10.0 calculated. ∃-500 Ŵ Corrected M2 Radius (km) 4.38 5.72 7.51 10.1 The maximum increase in focal Focal size at BDA with R2 = 4.38 km 16.8 21.0 optimized for 5 keV (µm), FWHM spot size (FWHM) after bending when compared to a theoretical -1.1E<sup>-06</sup> Corrected M2 Angle **-**1.4E<sup>-05</sup> -9.0E<sup>-06</sup> -5.0E<sup>-06</sup> mirror without a thermal bump is (degrees) Focal position relative to BDA (m) -1.7 -1000 -500 0 500 1000 0 500 1000 -1000 -500 only 0.2 microns. Horizontal position (µm) Horizontal position (µm)

# **FURTHER OPTIMIZATION**

Notch Design

- It has been shown that slope errors can be reduced by an order of magnitude by adding a notch to the side and only applying cooling above the notch[2-3].
- A notch of 8 mm x 7.5 mm was determined to be the optimal size notch for 5 keV.
- Analysis conducted with this notch size on the M1 mirror produced such a flat thermal bump that the focal spot size increased by only 0.2 microns.



#### **Internally Cooled**

- Recent improvements in internally cooled mirrors also make them a viable option to reduce slope errors compared to side cooled mirrors [4].
- Analysis conducted was on an internally cooled mirror with seven channels placed 1 mm below the optical surface that are 1 mm wide by 6 mm high.
- FEA results show that an order of magnitude reduction in slope error is possible as compared to side cooled



The small increase in focal size could potentially eliminate the need for bending the M2 Mirror.

mirrors. Unfortunately, the slope error is a shape that is not correctable by the M2 mirror.

## CONCLUSIONS

Based on the modeling, a focal size very close to the theoretical beam size one obtains without thermal distortions can be achieved by bending the M2 Mirror. This approach will allow the end station of the ISN Beamline to be able to achieve focal sizes of 20 nm or less. Preliminary results show that the notch and internally cooled mirror designs will greatly reduce the beam distortion due to thermal deformation. While these calculations show promise for reducing slope errors by an order or magnitude or greater, empirical studies need to be conducted to confirm these results.

formation

ð

 $\Box$ 

# REFERENCES

[1] A. Khounsary, D. Chojnowski, L. Assoufid, and W. Worek, "Thermal contact resistance across a copper-silicon interface" (SPIE '97) [2]L. Zhang, et al. "Thermal distortion minimization by geometry optimization for water-cooled white beam mirror or multilayer optics" (SRI 2012) [3]A. Khounsary., "Thermal Management of Next-Generation Contact-Cooled Synchrotron X-Ray Mirrors" SPIE annual meeting [4] A. Khounsary, "Design, fabrication, and evaluation of an internally cooled silicon carbide mirror"



\* Work at the Advanced Photon Source is supported by the U. S. Department of Energy, Office of Science, Office of Basic Energy Sciences, under Contract No. DE-AC02-06CH11357.

